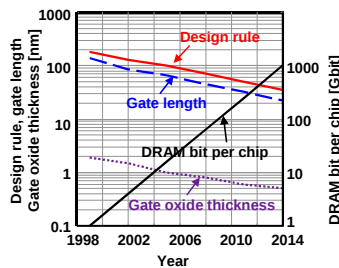


スーパーコネクต์(基調講演)

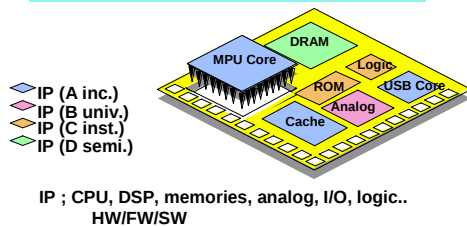
東京大学、国際・産学共同研究センター
生産技術研究所
桜井貴康
E-mail: tsakurai@iis.u-tokyo.ac.jp

Moore's Law



System on a Chip (SoC)

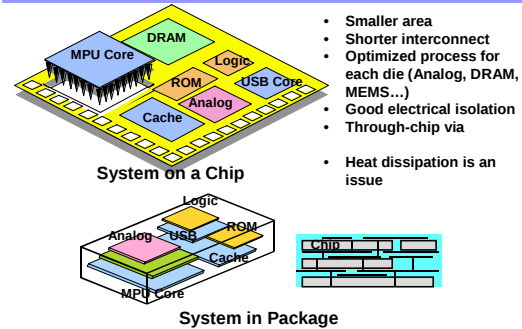
- Re-use and sharing of design
- Design in higher abstraction



Issues in System-on-Chip

- Un-distributed IP's (i.e. CPU, DSP of a certain company)
- Low yield due to larger die size
- Huge initial investment for masks & development
- IP testability, upfront IP test cost
- Process-dependent memory IP's
- Difficulty in high precision analog IP's due to noise
- Process incompatibility with non-Si materials and/or MEMS

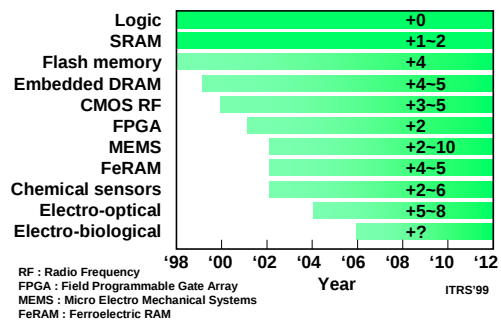
System in Package



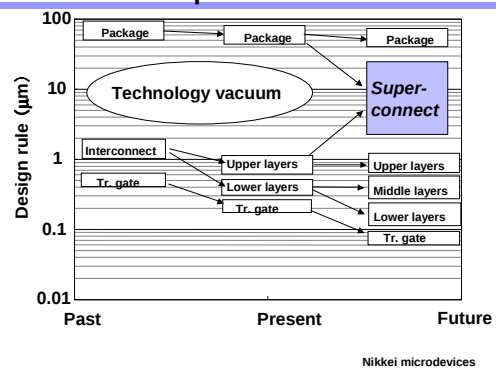
System-in-Packageの課題

- Special design tools for placement & route for co-design of LSI's and assembly
- High-density reliable substrate and metallization technology
- low-cost, available known good die (reworkability and module testing)

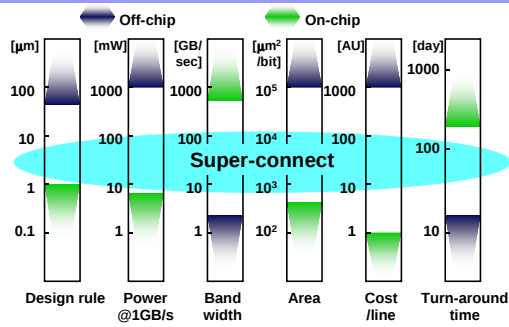
Technologies integrated on a chip



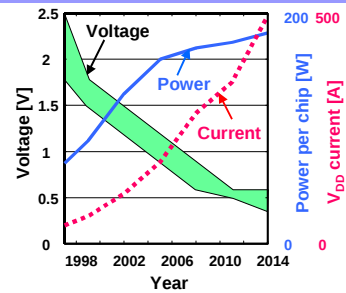
Super-connect



Super-connect



VDD, Power and Current Trend

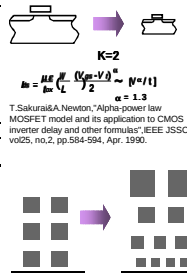


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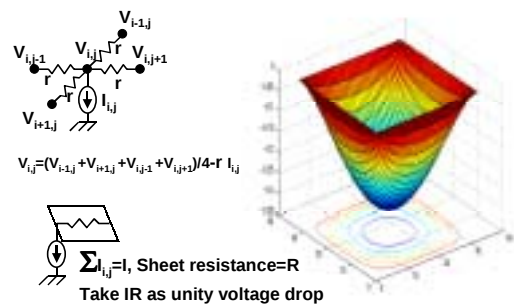
Scaling Law

Transistors		Scaling coefficients	
V_{DD}	[V]	1/k	
Tr. dimensions	[μm]	1/k	
Drain current	[$I \sim 1/x \times V^{1.3}$]	1/k ^{0.3}	
Gate capacitance	[C $\sim 1/x \times d$]	1/k	
Tr. delay	[d $\sim CV/I$]	1/k ^{1.7}	
Tr. power	[P $\sim VI \sim CV^2/d$]	1/k ^{1.3}	
Power density	[p $\sim P/k$]	k ^{0.7}	
Tr. density	[n $\sim 1/k$]	k ²	

Interconnects		Scaling coefficients	
Type	Scaling scenario	Local Scaled	Global Anti-scaled
Line thickness	[H]	1/k	k
Width	[W]	1/k	k
Separation	[S]	1/k	k
Oxide thickness	[H]	1/k	1
Length	[L]	1/k	1
Resistance	[$R_{int} \sim LW/T$]	k	1/k ²
Capacitance	[$C_{int} \sim LW/H$]	1/k	k
RC delay/Tr. delay	[D $\sim RC_{int}/d$]	k ^{2.7}	k ^{0.7}
Current density	[J $\sim PW/LW/T$]	—	k ^{0.7}
DC noise / V_{DD}	[N $\sim JWTR/V$]	—	k ^{2.7}

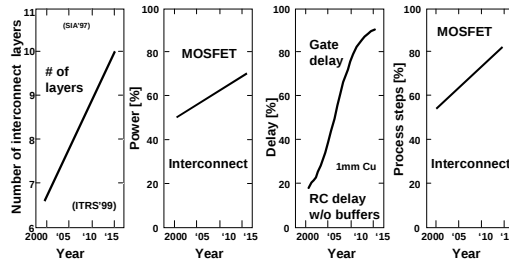


IR Drop



Interconnect determines cost & perf.

P: Power, D: Delay, A: Area, T: Turn-around



Interconnect Cross-Section and Noise

Unscaled / anti-scaled

- Clock
- Long bus
- Power supply

Scaled interconnect

- Signal

1V 20W $\rightarrow$ 20A current

2% noise on VDD & VSS $\rightarrow$ $\sim 0.02V / 20A \rightarrow \sim 10\mu\text{m}$ thick Cu
Thick layer interconnect, area pad, package are co-designed.

DSM interconnect design issues

Larger current

- IR drop (static and dynamic)
- Reliability (electro-migration)

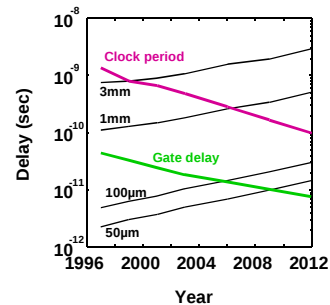
Smaller geometry / Denser pattern

- RC delay
- Signal Integrity
- Crosstalk noise
- Delay fluctuation

Higher speed

- Inductance
- EMI

RC delay and gate delay



Repeaters

C_T R_T C_{INT} R_{INT}

a) Without repeaters b) With repeaters

$t_{05} = 0.377 R_{INT} C_{INT} + 0.693 (R_T C_T + R_T C_{INT} + R_{INT} C_T)$

C_0 : Gate capacitance of minimum MOSFET
 R_0 : Gate effective resistance of minimum MOSFET

$Delay = k \left[p_1 \frac{R_{INT} C_{INT}}{k} + p_2 \left(\frac{R_0}{h} h C_0 + \frac{R_0 C_{INT}}{h} + \frac{R_{INT} h C_0}{k} \right) \right]$: Buffered

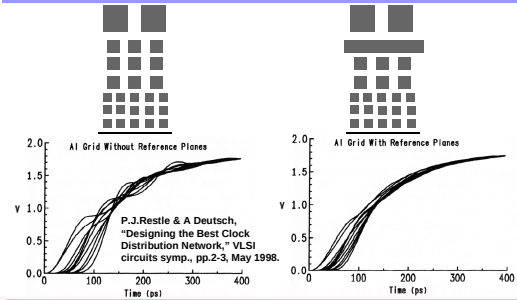
$\frac{\partial Delay}{\partial h} = 0 \rightarrow h_{OPT} = \sqrt{\frac{C_{INT} R_0}{R_{INT} C_0}}$: Optimized size of buffer inverter

$\frac{\partial Delay}{\partial k} = 0 \rightarrow k_{OPT} = \sqrt{\frac{p_1}{p_2} \frac{R_{INT} C_{INT}}{R_0 C_0}}$: Optimized number of stages

$Delay_{OPT} = 2 \sqrt{p_1 p_2 + p_2} \sqrt{R_{INT} C_{INT} R_0 C_0} = 2.4 \sqrt{\tau_{INT} \tau_{MOS}}$

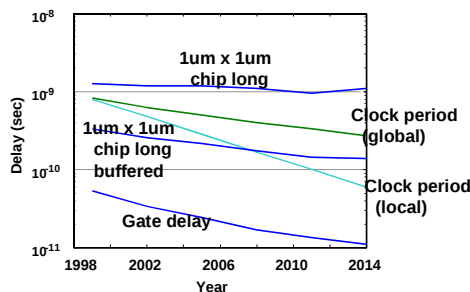
$Cap. \text{ of gates} = k_{OPT} h_{OPT} C_0 = \sqrt{p_1 / p_2} C_{INT} = 0.73 C_{INT}$

Inductive Effects in Clock Lines

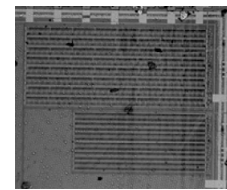
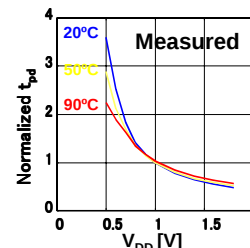


Board design practice is imported in LSI.

Buffered interconnect delay



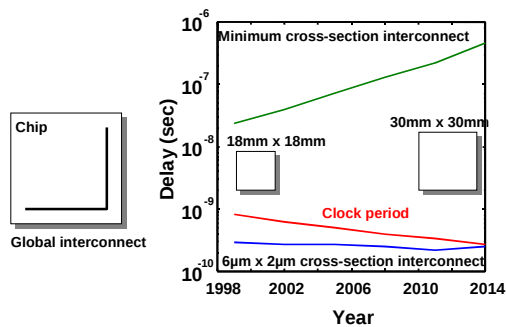
0.5V LSIでの逆温度特性



Photograph of 32bit FA
0.3um CMOS

K.Kanda, K.Nose, H.Kawaguchi, and T.Sakurai, "Design Impact of Positive Temperature Dependence of Drain Current in Sub 1V CMOS VLSI's", CICC99, pp.563-566, May 1999.

RC delay of global interconnections

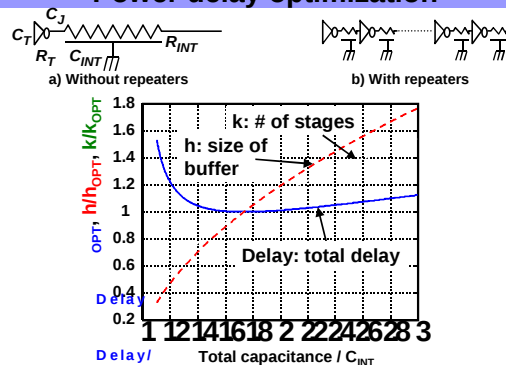


LSI in 2014

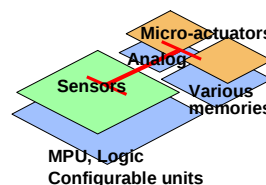
Year	Unit	1999	2014	Factor
Design rule	um	0.18	0.035	0.2
Tr. Density	/cm ²	6.2M	390M	30
Chip size	mm ²	340	900	2.6
Tr. Count per chip (uP)		21M	3.6G	170
DRAM capacity	1G	1T	1000	
Local clock on a chip	Hz	1.2G	17G	14
Global clock on a chip	Hz	1.2G	3.7G	3.1
Power	W	90	183	2.0
Supply voltage	V	1.5	0.37	0.2
Current	A	60	494.6	8
Interconnection levels		6	10	1.7
Mask count		22	28	1.3
Cost / tr. (packaged)	ucents	1735	22	0.01
Chip to board clock	Hz	500M	1.5G	3.0
# of package pins		810	2700	3.3
Package cost	cents/pin	1.61	0.75	0.5

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Power delay optimization



Possible electronic system in 2014



- Sensors/actuators
- 0.035um 3.6G Si FET's with VTH & VDD control
- Locally synchronous 17GHz clock, globally asynchronous
- Chip / Package / Board system co-design for power lines, clocks, and long wires (super-connect)